

Patent claims

1. A magnetically passive position sensor having a magnet arranged on a pivoting arm and having a large number of contact spring elements arranged in the pivoting range of the magnet, the contact spring elements lying opposite a thick film mesh, and it being possible for the contact spring elements to be moved by the magnet toward the thick film mesh, characterized in that the magnet (2) is held such that it cannot rotate about its mechanical axis (11), which points toward the thick film mesh (4), and is arranged with its magnetic axis (12) pointing in an intended direction.
2. The position sensor as claimed in claim 1, characterized in that the magnet (2) has a guide polygon (8), and in that the pivoting arm (1) is designed so as to correspond to the guide polygon (8).
3. The position sensor as claimed in claim 1 or 2, characterized in that at least one of the contact spring elements (5, 6) is arranged on a connection between a magnetic axis (12) and a mechanical axis (11) of the magnet (2).
4. A method for manufacturing a magnetically passive position sensor in which a magnet is arranged such that it can pivot over contact spring elements lying opposite a thick film mesh, characterized in that a magnetic axis of the magnet is determined, and in that the magnetic axis of the magnet is aligned with that contact spring element which is the least remote.
5. The method as claimed in claim 4, characterized in that a guide polygon is incorporated in the magnets once the alignment of the magnetic axis has been determined.